

GAY 1765 #6

PATENT

**In the United States Patent and Trademark Office**

Applicants: Julia S. Svirchevski et al.

Applicants' Reference: LAM1P109

Application No. 09/336,401 ✓

Filed: June 18, 1999

Title: POST-PLASMA PROCESSING WAFER  
CLEANING METHOD AND SYSTEM

Examiner: Unassigned

Group Art Unit: 1765

Date: June 15, 2000

**CERTIFICATE OF MAILING**

I hereby certify that this correspondence is being deposited with the United States Postal Service as First Class Mail in an envelope addressed to: Assistant Commissioner for Patents, Washington, DC 20231 on June 15, 2000.

Signed:

*Diane Schwanbeck*  
Diane Schwanbeck

**Separate Letter to the Official Draftsperson**

Assistant Commissioner for Patents  
Box: Official Draftsperson  
Washington, D.C. 20231

Dear Sir:

Applicants hereby attach twelve (12) sheets of formal drawings (Figures 1A, 1B, 1C, 1D, 1E, 2A, 2B, 2C, 2D, 3A, 3B, 3C, 3D, 4, 5, and 6) for the above-referenced patent application. In the event the Draftsperson has any questions concerning the formal drawings, he or she is respectfully requested to contact the undersigned. If any fees are due in connection with the filing of these drawings, then please charge such fees to our Deposit Account No. 50-0805 (Order No. LAM1P109).

Respectfully submitted,  
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